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Attorney Docket No.: 8021-55 (SS-14743-US)

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

APPLICANT: Jong-won Lee

Examiner: Maria F. Guerrero

Serial No.: 09/899,627

Group Art Unit: 2822

Filed: July 05, 2001

For: SOLUTION FOR CHEMICAL MECHANICAL POLISHING AND  
METHOD OF MANUFACTURING COPPER METAL  
INTERCONNECTION LAYER USING THE SAME

Assistant Commissioner for Patents  
Washington, D.C. 20231

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**RESPONSE TO OFFICE ACTION**  
**SETTING FORTH A RESTRICTION REQUIREMENT**


Sir:

In response to the Office Action of June 06, 2002, Applicants hereby elect claims 12-26  
for prosecution in this case, with traverse.

**CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(A)**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first  
class mail, postal in an envelope, addressed to the: Assistant Commissioner for Patents, Washington, D.C. 20231  
on 6/26/02.

Dated: 6/26/02

  
Frank Chau